

**AMENDMENTS TO THE ABSTRACT OF THE DISCLOSURE:**

Please replace the Abstract of the Disclosure with the following new Abstract.

~~It is an object of the present invention to provide a~~ corrosion resistant thermal type mass flow rate sensor, and a fluid supply device ~~employing for which the sensor is employed,~~ are provided thus allowing ~~to enhanced~~ corrosion resistance of the thermal type mass flow rate sensor, improve responsiveness, ~~achieve to be~~ achieved particle-free, and to prevent unevenness of product qualities. A

~~Concretely,~~ a thermal type mass flow rate sensor is constituted with a sensor part 1 comprising a corrosion resistant metal substrate 2 formed ~~as to be~~ a thin plate by applying electrolytic etching on the rear face side of a corrosion resistant metal material W, ~~and a thin film F to forming~~ a temperature sensor 3 and a heater 4 mounted on the rear face side of the said corrosion resistant metal substrate 2, and a sensor base 13 hermetically fitted by welding to the outer periphery of the corrosion resistant metal substrate 2 of the afore-mentioned sensor part 1 fitted into a fixture groove 13a.